Claim Amendments

Please amend claims 1, 4, and 19 as follows:

Listing of Claims

1. (currently amended) A method for fabricating an integrated circuit planar inductor with an enhanced Q value comprising:

providing a substrate comprising a dielectric layer over a semiconductor substrate;

forming over the substrate a planar spiral conductor layer comprising a single spiral to form a planar spiral inductor, wherein a successive series of loops within the planar spiral conductor layer is formed with a progressive and discontinuous variation, said variation progressing from a center of said spiral defined by a first loop to a periphery of said series of loops at least one of:

a series of progressive stepwise changes in linewidths to form a series of discrete linewidths for the successive series of loops; and

a series of progressive stepwise changes in spacings separating the successive series of loops;

wherein said center of said spiral defined by said first loop surrounds a planar surface of said dielectric layer to define an inner cavity.

Claims 2-3 (cancelled)

4. (currently amended) A method for fabricating an integrated circuit planar inductor with an enhanced Q value comprising:

providing a substrate comprising a dielectric layer over a semiconductor substrate;

forming on the substrate a planar spiral conductor layer to form a planar spiral inductor, wherein a successive series of loops within the planar spiral conductor layer is formed with a progressive and discontinuous variation, said variation progressing in any direction from a center of said spiral defined by a first loop to a periphery of said series of loops, said variation comprising at least one of:

a series of progressive stepwise changes in linewidths to form a series of discrete linewidths for the successive series of loops; and

a series of progressive stepwise changes in spacings separating the successive series of loops;

wherein the successive series of loops is formed in a shape selected from the group consisting of a triangle, a square, a rectangle, a higher order polygon, a uniform ellipse and a circle, wherein said center of said spiral defined by said first loop consists of surrounds a planar surface of said dielectric layer to define an inner cavity.

- 5. (original) The method of claim 1 wherein the planar spiral conductor layer is formed of a conductor material selected from the group consisting of non-magnetic metal, non-magnetic metal alloy, magnetic metal, magnetic metal alloy, doped polysilicon and polycide conductor materials, and laminates thereof.
- 6. (previously presented) The method of claim 1 wherein the progressive stepwise changes to form a series of discrete linewidths increases from the first loop which defines the center of the planar spiral inductor having a comparatively narrow linewidth to a final loop which defines the perimeter of the planar spiral inductor having a comparatively wide linewidth.
- 7. (original) The method of claim 6 wherein the comparatively narrow linewidth is from about 7 to about 10 microns and the comparatively wide line width is from about 17 to about 21 microns.
- 8. (previously presented) The method of claim 1 wherein the successive series of loops comprising the single spiral comprises from about 1 to about 8 loops.

Claims 9-15 (cancelled)

16. (previously presented) The method of claim 1 wherein the progressive and discontinuous variation comprises progressively increasing or decreasing stepwise changes.

- 17. (previously presented) The method of claim 1, wherein the successive series of loops is formed in a shape selected from the group consisting of a triangle, a square, a rectangle, a higher order polygon, a uniform ellipse and a circle.
 - 18. (previously presented) The method of claim 4 wherein the progressive stepwise changes to form a series of discrete linewidths increases from a first loop which defines the center of the planar spiral inductor having a comparatively narrow linewidth to a final loop which defines the perimeter of the planar spiral inductor having a comparatively wide linewidth.
 - 19. (currently amended) A method for fabricating an integrated circuit planar inductor with an enhanced Q value comprising:

providing a substrate comprising a dielectric layer over a semiconductor substrate;

forming over the substrate a planar spiral conductor layer comprising a single spiral to form a planar spiral inductor, wherein a successive series of loops within the planar spiral conductor layer is formed with a progressive and discontinuous variation, said variation progressing in any direction from a center of said spiral defined by a first loop to a periphery of said series of loops, said variation comprising a series of progressive stepwise changes in spacings separating the successive series of loops;

wherein said center of said spiral defined by said first
loop surrounds a planar surface of said dielectric layer to
define an inner cavity.

- 20. (previously presented) The method of claim 19 wherein said variation further comprises a series of progressive stepwise changes in linewidths to form a series of discrete linewidths for the successive series of loops.
- 21. (previously presented) The method of claim 20 wherein the progressive stepwise changes to form a series of discrete linewidths increases from a first loop which defines the center of the planar spiral inductor having a comparatively narrow linewidth to a final loop which defines the perimeter of the planar spiral inductor having a comparatively wide linewidth.
- 22. (previously presented) The method of claim 19, wherein the progressive and discontinuous variation comprises progressively increasing or decreasing stepwise changes.
- 23. (cancelled)
- 24. (previously presented) The method of claim 1, wherein the

successive series of loops is formed in a shape selected from the group consisting of a triangle, a square, a rectangle, and a higher order polygon.